**Amendments to the Claims:**

This listing of claims will replace all prior versions, and listings, of claims in the application:

**Listing of Claims:**

Claims 1 to 7. (Canceled).

8. (Currently Amended) A micromechanical yaw rate sensor, comprising:

a substrate;

a bridge;

an anchoring device provided on the substrate and including two opposite bases that are connected fixedly with the substrate and that are connected with one another via the bridge;

a flexural spring device; and

an annular flywheel that is connected via the flexural spring device with the anchoring device such that an area of connection with the anchoring device is located essentially in a center of a ring of the flexural spring device, so that the annular flywheel is displaceable, elastically from a rest position, about an axis of rotation situated perpendicular to a surface of the substrate, and about at least one axis of rotation situated parallel to the surface of the substrate, wherein:

at least one V-shaped flexural spring of the flexural spring device is attached to each of opposite sides of the bridge in such a way that an apex is situated on the bridge and limbs of the ~~bridge~~ V-shaped flexural spring are spread towards the annular flywheel with an opening angle other than 90 degrees.

9. (Original) The micromechanical yaw rate sensor according to claim 8, wherein:

the at least one V-shaped flexural spring includes a first V-shaped flexural spring and a second V-shaped flexural spring, and

the opening angle is equal for the first V-shaped flexural spring and the second V-shaped flexural spring.

10. (Original) The micromechanical yaw rate sensor according to claim 9, wherein:

the first V-shaped flexural spring and the second V-shaped flexural spring are attached to the bridge such that the first V-shaped flexural spring and the second V-shaped flexural spring form an X shape.

11. (Original) The micromechanical yaw rate sensor according to claim 10, wherein:

the opening angle is selected such that a natural frequency about the axis of rotation situated perpendicular to the surface of the substrate is smaller than each natural frequency about the axis of rotation situated parallel to the surface of the substrate.

12. (Original) The micromechanical yaw rate sensor according to claim 8, wherein:

the two opposite bases are in the shape of a wedge and include two wedge tips, and the bridge connects the two wedge tips with one another.

13. (Original) The micromechanical yaw rate sensor according to claim 8, wherein:

the bridge is suspended freely over the substrate from the two opposite bases.

14. (Original) The micromechanical yaw rate sensor according to claim 8, wherein:

the micromechanical yaw rate sensor can be manufactured using one of silicon surface micromechanical technology and another micromechanical technology.

15. (New) A micromechanical yaw rate sensor, comprising:

a substrate;

a bridge;

an anchoring device provided on the substrate and including two opposite bases that are connected fixedly with the substrate and that are connected with one another via the bridge;

a flexural spring device; and

an annular flywheel that is connected via the flexural spring device with the anchoring device such that an area of connection with the anchoring device is located essentially in a center of a ring of the flexural spring device, so that the annular flywheel is displaceable, elastically from a rest position, about an axis of rotation situated perpendicular to a surface of

the substrate, and about at least one axis of rotation situated parallel to the surface of the substrate;

wherein at least one V-shaped flexural spring of the flexural spring device is attached to each of opposite sides of the bridge in such a way that an apex is situated on the bridge and limbs of the V-shaped flexural spring are spread towards the annular flywheel with an opening angle; and

wherein the opening angle is selected such that a natural frequency about the axis of rotation situated perpendicular to the surface of the substrate is smaller than each natural frequency about the axis of rotation situated parallel to the surface of the substrate.